ISC Audits & Reviews SC Summary (Jan, 2020)

Doc.	Title	Results
6168	Line item Revision for SEMI M67 “Test Method For Determining Wafer Near-Edge Geometry From A measured Thickness Data Array Using The ESFQR, ESFQD And ESBIR Metrics" to add exclusion windows to prevent distorted area data. Line Item 1 - Adding exclusion windows to determine valid sector for ZDD	Passed
6505;	Line item Revision for SEMI M68 “Test Method For Determining Wafer Near-Edge Geometry From A Measured Thickness Data Array Using Curvature Metric, ZDD” to add exclusion windows to prevent distorted area data Line Item 1 - Adding exclusion windows to determine valid sector for ZDD	Passed
6548A;	Line Item Revision to SEMI E170: Specification For Secured Foundation Of Recipe Management System (SFORMS) Line Item 1 - Put Application Note which includes sequence diagram and transition of IDs instead of Figure 9.	Passed

For more information, please contact the SEMI Standards Engineer/Coordinator. (http://www.semi.org/standards/contacts) nearest you.

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Jan 30, 2020